ABSTRACT

A piezoelectric focusing apparatus and method for the same are proposed to quickly adjust a distance between a lens unit and an electronic imaging device. An expanding table associated with increased voltage and a shrinkage table associated with decreased voltage for the piezoelectric material is constructed. A bi-directional deformation table is then established by associating voltages on the expanding table and the shrinkage table corresponding to the same deformation. A voltage is supplied to the piezoelectric material according to the bi-directional deformation table for generating a desired deformation and controlling a focusing distance between the lens unit and the electronic imaging device.